EE 330 Lecture 19

Guest Speaker: David Ripley of Skyworks Bipolar Device Operation and Modeling

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Motorola Design and Development TDMA and Amplifies 1992-1999 Skyworks Solutions (Conexant) Senior Technical Director 1999-Present Currently holds 150 patents





A Single Chip HBT Power Amplifier with Integrated Power Control

David Ripley – Skyworks Solutions, Inc. RTU2B-1

SKYWORKS® BREAKTHROUGH SIMPLICITY





Outline

- Goals for this work
- Solution Block Diagram
- Circuit Schematic Details
- Device Layout
- Measured Performance
- Summary



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Introduction

- Goal:
 - Develop a 2G PA solution maintaining the RF performance of HBT while delivering next generation size and cost



Reduce Size and Cost Through Die Elimination

Power Control Block Diagram



Indirect control of RF power through DC current



Importance of Squaring Response



~3x improvement in control slope



Voltage-to-Current Processing



Square Function Response



Process, Temperature, Supply insensitive design



Core Bias and Error Amplifier



PA Bias Interface



RF Power Amplifier Bias interface

Single Follower Switched for Dual Band Support



Power Amplifier



Complete HBT Die



Power Amplifier with Integrated Control

Module Power Control Accuracy



Significant Margin to 3GPP Standard

Burst Time Mask Performance



Transient satisfies time and spectral masks

Summary

- BiFET HBT technology enables integration of PA and control on a single die
- Circuit solutions were developed to meet all 3GPP systems standards with margin
- Detailed Device simulations are confirmed through extensive testing and through sustained high volume production

Thanks to Hongxiao Shao for PDK development, Pete Zampardi for process and modeling, Phil Lehtola for RF PA and module design, Robert Rammelsberg for design verification.



Review from last lecture

TABLE 2B.1 Process scenario of major process steps in typical n-well CMOS process^a

1.	Clean wafer	
2.	GROW THIN OXIDE	
3.	Apply photoresist	
4.	PATTERN n-well	(MASK #1)
5.	Develop photoresist	
6.	Deposit and diffus n-type impurities	
7.	Strip photoresist	
8.	Strip thin oxide	
9.	Grow thin oxide	
10.	Apply layer of Si ₃ N ₄	
11.	Apply photoresist	
12.	PATTERN Si_3N_4 (active area definition)	(MASK #2)
13.	Develop photoresist	
14.	Etch Si ₃ N ₄	
15.	Strip photoresist	
	Optional field threshold voltage adjust	
	A.1 Apply photoresist	
	A.2 PATTERN ANTIMOAT IN SUBSTRATE	(MASK #A1)
	A.3 Develop photoresist	
	A.4 FIELD IMPLANT p-type)	
	A.5 Strip photoresist	
16.	GROW FIELD OXIDE	
17.	Strip Si ₃ N ₄	
18.	Strip thin oxide	
19.	GROW GATE OXIDE	
20.	POLYSILICON DEPOSITION (POLY I)	
21.	Apply photoresist	
22.	PATTERN POLYSILICON	(MASK #3)
23.	Develop photoresist	
24.	ETCH POLYSILICON	



Review from last lecture Metal Mask



A-A' Section



B-B' Section

Review from last lecture

Should now know what you can do in this process !!

Can metal connect to active?

Can metal connect to substrate when on top of field oxide?

How can metal be connected to substrate?

Can poly be connected to active under gate?

Can poly be connected to active any place?

Can metal be placed under poly to isolate it from bulk?

Can metal 2 be connected directly to active?

Can metal 2 be connected to metal 1?

Can metal 2 pass under metal 1?

Could a process be created that will result in an answer of YES to most of above?

How does the minimum-sized inverter delay when driving an identical device compare between a 0.5u process and a 0.18u process?



How does the minimum-sized inverter delay when driving an identical device compare between a 0.5u process and a 0.18u process?







$$C_{IN} = C_{GSn} + C_{GSp}$$

 $t_{HL} = R_{PD}C_{IN}$ $t_{LH} = R_{PU}C_{IN}$ $t_{PROP} = t_{HL} + t_{LH}$ How does the minimum-sized inverter delay when driving an identical device compare between a 0.5u process and a 0.18u process?



It will also be shown later that if n inverters are connected in a loop and if n is odd, this will form a "ring" oscillator:



RUN: T91T TECHNOLOGY: SCN05

Run type: SKD

VENDOR: AMIS EATURE SIZE: 0.5 microns

INTRODUCTION: This report contains the lot average results obtained by MOSIS from measurements of MOSIS test structures on each wafer of this fabrication lot. SPICE parameters obtained from similar measurements on a selected wafer are also attached.

COMMENTS: American Microsystems, Inc. C5

TRANSISTOR PARAMETE	RS W/L	N-CHANNEL I	-CHANNEL	UNITS
MINIMUM Vth	3.0/0.6	0.81	-0.92	volts
SHORT	20.0/0.6			
Idss		466	-250	uA/um
Vth		0.69	-0.89	volts
Vpt		12.7	-11.7	volts
WIDE	20.0/0.6			
Ids0		< 2.5	< 2.5	pA/um
LARGE	20.0/20.0			
Vth		0.71	-0.94	volts
Vjbkd		8.8	-11.7	volts
Ijlk		<50.0	<50.0	рА
Gamma		0.44	0.57	V^0.5
K' (Vo*Cox/2) Low-field Mobility		54.8 434.84	-19.7 136.32	uA/V^2 cm^2/V*s

PROCESS PARAMETERS Sheet Resistance Contact Resistance Gate Oxide Thickness	N+ 85.3 59.6 137	P+ 111.2 145.4	РОLУ 22.4 17.9	PLY2_HR 1033	M1 0.09	UNITS ohms/sq ohms angstroms
CAPACITANCE PARAMETERS Area (substrate) Area (N+active) Area (P+active) Area (poly)	N+ 443	р+ 745	POLY 102 2518 2441	POLY2 896	м1 61	UNITS aF/um^2 aF/um^2 aF/um^2 aF/um^2
CIRCUIT PARAMETERS Ring Oscillator Freq. DIV256 (31-stg,5.0V) Ring Oscillator Power DIV256 (31-stg,5.0V)		94	UNIT .47 MHz .48 uW/M	CS Hz/gate		

MOSIS WAFER ACCEPTANCE TESTS

RUN: T4BK (MM_NON-EPI_THK-MTL) TECHNOLOGY: SCN018 VENDOR: TSMC FEATURE SIZE: 0.18 microns

INTRODUCTION: This report contains the lot average results obtained by MOSIS from measurements of MOSIS test structures on each wafer of this fabrication lot. SPICE parameters obtained from similar measurements on a selected wafer are also attached.

COMMENTS: DSCN6M018_TSMC

TRANSISTOR PARAMETERS	W/L	N-CHANNEL	P-CHANNEL	UNITS
MINIMUM	0.27/0.18			
Vth		0.50	-0.53	volts
SHORT	20.0/0.18			
Idss		571	-266	uA/um
Vth		0.51	-0.53	volts
Vpt		4.7	-5.5	volts
WIDE	20.0/0.18			
Ids0		22.0	-5.6	pA/um
LARGE	50/50			
Vth		0.42	-0.41	volts
Vjbkd		3.1	-4.1	volts
Ijlk		<50.0	<50.0	pА
K' (Uo*Cox/2)		171.8	-36.3	uA/V^2
Low-field Mobility		398.02	84.10	cm^2/V*s

CAPACITANCE PARAMETERS	N+	P+	POLY	Μ1	M2	MЗ	Μ4	M5	M6	R_W	D_N_W	M5P	N_W	UNITS
Area (substrate)	998	1152	103	39	19	13	9	8	3		129		127	aF/um^2
Area (N+active)			8566	54	21	14	11	10	9					aF/um^2
Area (P+active)			8324											aF/um^2
Area (poly)				64	18	10	7	6	5					aF/um^2
Area (metal1)					44	16	10	7	5					aF/um^2
Area (metal2)						38	15	9	7					aF/um^2
Area (metal3)							40	15	9					aF/um^2
Area (metal4)								37	14					aF/um^2
Area (metal5)									36			1003		aF/um^2
Area (r well)	987													aF/um^2
Area (d well)										574				aF/um^2
Area (no well)	139													aF/um^2
Fringe (substrate)	244	201		18	61	55	43	25						aF/um
Fringe (poly)				69	39	29	24	21	19					aF/um
Fringe (metal1)					61	35		23	21					aF/um
Fringe (metal2)						54	37	27	24					aF/um
Fringe (metal3)							56	34	31					aF/um
Fringe (metal4)								58	40					aF/um
Fringe (metal5)									61					aF/um
Overlap (P+active)			652											aF/um
CIRCUIT PARAMETERS						l	JNI.	ΓS						
Inverters			K			_	_							
Vinv		1	.0	(ð.74	4 v	volt	ts						
Vinv		1	.5	(9.78	3	volt	ts						
Vol (100 uA)		2	.0	(0.08	3	volt	ts						
Voh (100 uA)		2	.0	-	1.63	3	volt	ts						
Vinv		2	.0	(9.82	2	volt	ts						
Gain		2	.0	-23	3.33	3								
Ring Oscillator Freq.														
D1024_THK (31-stg_3	3V)			332	R 2'	2	MH⁊	•						
DIV1024 (31-stg,1.8V)			402	2.84	1 1	MHz							
Ring Oscillator Power														

 D1024_THK (31-stg,3.3V)
 0.07
 uW/MHz/gate

 DIV1024 (31-stg,1.8V)
 0.02
 uW/MHz/gate

How does the minimum-sized inverter delay compare between a 0.5u process and a 0.18u process?

Feature	0.5	0.18	Units
Vtn	0.81	0.5	V
Vtp	-0.92	-0.53	V
uCoxn	109.6	344	uA/V^2
uCoxp	39.4	72.6	uA/V^2
Сох	2.51	8.5	fF/µm^2
Vdd	5	1.8	V
fosc-31	94.5	402.8	MHz

Assume n-channel and p-channel devices with L=Lmin, W=1.5Lmin

0.18

0.83

1491

3941

1.23

3.26

223

0.5

1.88

1452

2858

2.73

5.38

123



$t_{HL} = R_{pd}C_L$	
$t_{LH} = R_{pd}C_L$	

Feature

CL

Rpd

Rpu

THL

TLH

f

$$R_{pd} = \frac{L_n}{\mu_n C_{OX} W_n (V_{DD} - V_{TN})}$$

$$R_{pu} = \frac{L_p}{\mu_p C_{OX} W_p (V_{DD} + V_{TP})}$$
0.18 Units

fF

ohms

ohms

psec

psec

GHz

$$\boldsymbol{C}_{L} = \boldsymbol{C}_{OX} \left(\boldsymbol{W}_{n} \boldsymbol{L}_{n} + \boldsymbol{W}_{p} \boldsymbol{L}_{p} \right)$$

Note 0.18u process is much faster than 0.5u process
Some scale even faster

Basic Devices and Device Models

- Resistor
- Diode
- Capacitor
- MOSFET
- BJT

Lets pick up a discussion of Technology Files before moving to BJT

Return to basic devices !

Basic Devices and Device Models

- Resistor
- Diode
- Capacitor
- MOSFET



Bipolar Junction Transistors

- Operation
- Modeling

Carriers in Doped Semiconductors

n-type

p-type



Carriers in Doped Semiconductors

	Majority Carriers	Minority Carriers
n-type	electrons	holes
p-type	holes	electrons





Carriers in electrically induced n-channel are electrons





Carriers in electrically induced p-channel are holes

Carriers in MOS Transistors



Carriers in channel of MOS transistors are Majority carriers



With proper doping and device sizing these form Bipolar Transistors



In contrast to a MOSFET which has 4 terminals, a BJT only has 3 terminals

Consider npn transistor – Forward Active Operation



Under forward BE bias current flow into base and out of emitter

- Current flow is governed by the diode equation
- Carriers in emitter are electrons (majority carriers)
- When electrons pass into the base they become minority carriers
- Quickly recombine with holes to create holes in base region
- Dominant current flow in base is holes (majority carriers)

Bipolar Operation Consider npn transistor – Forward Active Operation



Under forward BE bias and reverse BC bias current flows into base region

Carriers in emitter are electrons (majority carriers)

When electrons pass into the base they become minority carriers

When minority carriers are present in the base they can be attracted to collector

Bipolar Operation Consider npn transistor – Forward Active Operation



If no force on electron is applied by collector, electron will contribute to base current

Consider npn transistor – Forward Active Operation



If no force on electron is applied by collector, electron will contribute to base current Electron will recombine with a hole so dominant current flow in base will be by majority carriers

Consider npn transistor – Forward Active Operation



When minority carriers are present in the base they can be attracted to collector with reverse-bias of BC junction and can move across BC junction





When minority carriers are present in the base they can be attracted to collector with reverse-bias of BC junction and can move across BC junction

Will contribute to collector current flow as majority carriers







Some will recombine with holes and contribute to base current and some will be attracted across BC junction and contribute to collector

Size and thickness of base region and relative doping levels will play key role in percent of minority carriers injected into base contributing to collector current



Under forward BE bias and reverse BC bias current flows into base region

Carriers in emitter are electrons (majority carriers)

When electrons pass into the base they become minority carriers

When minority carriers are present in the base they can be attracted to collector

Minority carriers either recombine with holes and contribute to base current or are attracted into collector region and contribute to collector current



Minority carriers either recombine with holes and contribute to base current or are attracted into collector region and contribute to collector current

If most of the minority carriers are attracted to collector, $|I_c| \simeq |I_E|$ Thus $I_B << I_C$

Implications of this observation?

If input to device is I_B and output is I_C , the BJT will behave as a current amplifier with large current gain !! This was the key observation by Bell Labs in 1948 !!



Under forward BE bias and reverse BC bias current flows into base region

- Efficiency at which minority carriers injected into base region and contribute to collector current is termed $\boldsymbol{\alpha}$
- α is always less than 1 but for a good transistor, it is very close to 1
- For good transistors $.99 < \alpha < .999$
- Making the base region very thin makes α large



- principle of operation of pnp and npn transistors are the same
- minority carriers in base of pnp are holes
- npn usually have modestly superior properties because mobility of electrons is larger than mobility of holes



In contrast to MOS devices where current flow in channel is by majority carriers, current flow in the critical base region of bipolar transistors is by minority carriers



often 50<β<999



 β is typically very large

Bipolar transistor can be thought of as current amplifier with a large current gain In contrast, MOS transistor is inherently a tramsconductance amplifier $\mathbf{I}_{\mathsf{B}} = \widetilde{I}_{S} \mathbf{e}^{\frac{\mathsf{V}_{\mathsf{BE}}}{\mathsf{V}_{\mathsf{t}}}}$ $\mathbf{I}_{\mathsf{C}} = \beta \widetilde{I}_{S} \mathbf{e}^{\frac{\mathsf{V}_{\mathsf{BE}}}{\mathsf{V}_{\mathsf{t}}}}$ Current flow in base is governed by the diode equation

Collector current thus varies exponentially with V_{BF}



- The BJT I/O relationship is exponential in contrast to square-law for MOSFET
- Provides a very large "gain" for the BJT (assuming input is voltage and output is current)
- This property is very useful for many applications



Stay Safe and Stay Healthy !

End of Lecture 19